

PROCEEDINGS OF SPIE

Advances in X-Ray/EUV Optics and Components XVIII

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**22 August 2023
San Diego, California, United States**

Sponsored and Published by
SPIE

Volume 12694

Proceedings of SPIE 0277-786X, V. 12694

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Advances in X-Ray/EUV Optics and Components XVIII, edited by Hidekazu Mimura,
Ali M. Khounsary, Christian Morawe, Proc. of SPIE Vol. 12694, 1269401
© 2023 SPIE · 0277-786X · doi: 10.1117/12.3012878

Proc. of SPIE Vol. 12694 1269401-1

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Author(s), "Title of Paper," in *Advances in X-Ray/EUV Optics and Components XVIII*, edited by Hidekazu Mimura, Ali M. Khounsary, Christian Morawe, Proc. of SPIE 12694, Seven-digit Article CID Number (DD/MM/YYYY); (DOI URL).

ISSN: 0277-786X
ISSN: 1996-756X (electronic)

ISBN: 9781510666023
ISBN: 9781510666030 (electronic)

Published by
SPIE
P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time)
SPIE.org
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